

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

11/IDS
Cheresa
11-29-99

In re the Application of:

NISHIMOTO et al

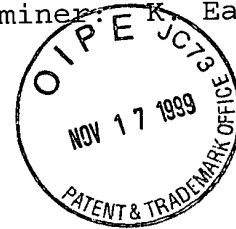
Serial No.: 08/897,839

Filed: July 21, 1997

For: STRESS-ADJUSTED INSULATING
FILM FORMING METHOD,
SEMICONDUCTOR DEVICE AND
METHOD OF MANUFACTURING THE
SAME

Group Art Unit: 2814

Examiner: K. Eaton



INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97(b)(1)

Assistant Commissioner for Patents
Washington, D.C. 20231

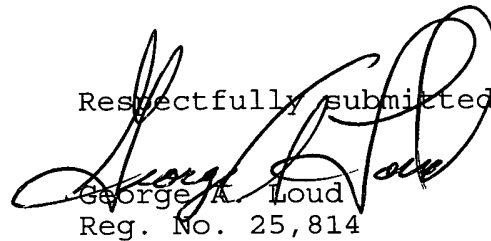
Sir:

It is respectfully requested that the five (5) Japanese Kokai publications (published, unexamined Japanese applications) which are listed on the attached, be considered in connection with examination of the captioned Continuing Prosecution Application (CPA). Copies of each of the listed Kokai publications are submitted herewith, along with a published English language abstract for each. Also submitted herewith is a copy of an office action dated October 26, 1999 which was issued in connection with Japanese Application No. 8-346351, by which office action the five (5) Kokai publications submitted here were first brought to the attention of the applicants and their agents. The examiner will note that the Japanese office action of October 26, 1999 issued in connection with Japanese Application No. 8-346351, the priority of which is claimed in the captioned application and, on information

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and belief, Japanese Application No. 8-346351 corresponds to the captioned application.

Respectfully submitted,



George A. Loud
Reg. No. 25,814

Dated: November 17, 1999

LORUSSO & LOUD
3137 Mt. Vernon Avenue
Alexandria, VA 22305

(703) 739-9393